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|-------------------------------|------------------------|---------------------|--|
| Notice of Allowability | Application No. | Applicant(s) | |
| | 10/800,369 | OH, HILARIO L. | |
| | Examiner | Art Unit | |
| | Thomas K. Pham | 2121 | |

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. ☒ This communication is responsive to amendment filed 5/18/2006.
2. ☒ The allowed claim(s) is/are 1-20.
3. ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
 - a) ☐ All b) ☐ Some* c) ☐ None of the:
 1. ☐ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. _____.
 3. ☐ Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

* Certified copies not received: _____.

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.

THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.

4. ☐ A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
5. ☐ CORRECTED DRAWINGS (as "replacement sheets") must be submitted.
 - (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached
 - 1) ☐ hereto or 2) ☐ to Paper No./Mail Date _____.
 - (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date _____.

Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).
6. ☐ DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

Attachment(s)

- | | |
|---|--|
| 1. <input type="checkbox"/> Notice of References Cited (PTO-892) | 5. <input type="checkbox"/> Notice of Informal Patent Application (PTO-152) |
| 2. <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | 6. <input type="checkbox"/> Interview Summary (PTO-413), Paper No./Mail Date _____. |
| 3. <input type="checkbox"/> Information Disclosure Statements (PTO-1449 or PTO/SB/08), Paper No./Mail Date _____ | 7. <input type="checkbox"/> Examiner's Amendment/Comment |
| 4. <input type="checkbox"/> Examiner's Comment Regarding Requirement for Deposit of Biological Material | 8. <input checked="" type="checkbox"/> Examiner's Statement of Reasons for Allowance |
| | 9. <input type="checkbox"/> Other _____. |

Reasons for Allowance

1. Claims 1-20 are allowed.
2. The following is an examiner's statement of reasons for allowance:

While Hunter (U.S. Patent No. 6,707,545) discloses a system for inspecting a substrate in a processing system. The system provides multiple inspection collection points on a semiconductor processing system. The system transmits signals representing surface topographical characteristics of the substrate, at a particular process, to a process monitoring controller configured to operate one or more optical inspection systems. The process monitoring controller determines the state of the particular substrate surface with respect to a reference substrate value. Hunter does not teach operating said track system responsive to a signal from a track system clock; pre-determining and inserting pre-planned wait states as needed to avoid conflict for resources in said semiconductor wafer fabrication system prior to operating said semiconductor wafer fabrication system; determining deviation from nominal timing in said scanner system clock; dynamically inserting time delays as needed in said semiconductor wafer fabrication system to compensate for a determined deviation; and other limitations related to these features in combination with the remaining elements and features of the claimed invention.

And Kimmel (U.S. Patent No. 4,850,027) discloses a parallel pipeline processing to a generalized network of processing elements and image combination elements having neighborhood function logic with a feedback connection, thus providing as output a composite function of the current image plus the previous image. The system features configurable unitary processing element groups (PEGs), each PEG having a number of processing elements (PEs) and boolean combiner image switches (BC) arrayed in image processing subassembly having

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significant configurability. Kimmel does not teach operating said track system responsive to a signal from a track system clock; pre-determining and inserting pre-planned wait states as needed to avoid conflict for resources in said semiconductor wafer fabrication system prior to operating said semiconductor wafer fabrication system; and other limitations related to these features in combination with the remaining elements and features of the claimed invention.

The prior art of record fails to teach or fairly suggest to one of ordinary skill in the art at the time of the invention, in conjunction with all the other claimed limitations, a semiconductor wafer fabrication system having all the claimed features of applicant's instant invention, specifically including: operating said track system responsive to a signal from a track system clock; pre-determining and inserting pre-planned wait states as needed to avoid conflict for resources in said semiconductor wafer fabrication system prior to operating said semiconductor wafer fabrication system; determining deviation from nominal timing in said scanner system clock; dynamically inserting time delays as needed in said semiconductor wafer fabrication system to compensate for a determined deviation, etc., as set forth in the claims.

Also, there is no motivation to combine the Hunter reference with the Kimmel reference to meet these limitations. It is for these reasons that applicant's invention defines over the prior art of record.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

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Any inquiry concerning this communication or earlier communications from the examiner should be directed to examiner *Thomas Pham*; whose telephone number is (571) 272-3689, Monday to Thursday from 6:30 AM - 5:00 PM EST or contact Supervisor *Mr. Anthony Knight* at (571) 272-3687.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Thomas Pham

Patent Examiner

A handwritten signature in black ink, appearing to read 'thumpham', with a long, sweeping horizontal line extending to the right.

June 26, 2006